

	Room A (605-606)	Room B (607)	Room C (608)	Room D (610)
9:00	<p>TA1: 3D-1 TA1-1 TSV MEOL (Mid-End-Of-Line) and its Assembly / Packaging Technology for 3D/2.5D Solutions Seung Wook Yoon, STATS ChipPAC / Singapore</p> <p>TA1-2 Through-Package-Via formation technique by laser ablation and reliability of TPVs in glass Yoichiro Sato¹, Kenji Kitaoka², Motoshi Ono², Mitsuru Watanabe², Vijay Sukumaran³, Kaya Demir³, Venky Sundaram³, Rao R Tummala³, 1AGC Electronics America, 2Asahi Glass, 3Georgia Institute of Technology / USA</p> <p>TA1-3 Effect of Underfill Properties on Thermomechanical Stress in Fine Pitch 3D-IC Package Akihiro Horibe, Sayuri Kohara, Kuniaki Sueoka, Keiji Matsumoto, Yasumitsu Orii, Fumiaki Yamada, ASET / Japan</p> <p>TA1-4 High Thermal Conductive Inter Chip Fill Material for 3D-IC Yasuhiro Kawase¹, Makoto Ikemoto¹, Toshiyuki Suzuki¹, Tomohide Murase¹, Hideki Kiritani¹, Takayoshi Hirai¹, Keiji Matsumoto², Akihiro Horibe², Yasumitsu Orii², 1Mitsubishi Chemical, 2IBM Japan / Japan</p>	<p>TB1: Printed-1 TB1-1 <Session Invited> (50min.) Broad Implications Arising from Novel Sintering Process and Conductive Inks for Printed Electronics Stan Farnsworth, NovaCentrix / USA</p> <p>TB1-2 <Session Invited> (50min.) Printed transistors for ambient electronics Takao Someya, The University of Tokyo / Japan</p>	<p>TC1: RF TC1-1 Effect of Periodic Dielectric Material placed over PCB on EM Noise Shielding Yoshiki Kayano, Hiroshi Inoue, Akita University / Japan</p> <p>TC1-2 Examination of the Reduction Technique of Radiation Noise from the Power Supply Layers in PCB Hitoshi Takakura, Shinichi Sasaki, Saga University / Japan</p> <p>TC1-3 A Broadband Antenna with Fan-Shaped and Trapezoidal Elements for Ultra Wideband Radio Fukuro Koshiji, Shunsuke Itaya, Yusuke Akiyama, Kokushikan University / Japan</p> <p>TC1-4 A Bent Unbalanced Dipole Antenna with Semicircular and Trapezoidal Radiators for Ultra Wideband Radio Yusuke Akiyama¹, Fukuro Koshiji¹, Kohji Koshiji², 1Kokushikan University, 2Tokyo University of Science / Japan</p>	<p>TD1: MEMS-1 TD1-1 Parylene deposition aided ionic liquid on Polyethersulfone (PES) membrane for potential use in nanofiltration Gunawan Setia Prihandana, Hikaru Ito, Norihisa Miki, Keio University / Japan</p> <p>TD1-2 Human position sensing device with high conductive polymer-coated fibers Seiichi Takamatsu¹, Takahiko Imai¹, Takahiro Yamashita¹, Toshihiro Itoh², 1BEANS Laboratory, 2National institute for advanced industrial science and technology / Japan</p> <p>TD1-3 Selectively Controlled Alignment of Single Carbon Nanotube Bundles by Dielectrophoresis Takuma Chikamoto¹, Yuichiro Shimada¹, Mitsuo Umetsu², Masakazu Sugiyama³, 1BEANS PROJECT, 2The University of Tohoku, 3The University of Tokyo / Japan</p> <p>TD1-4 CMOS Neural Networks Controlled MEMS Micro Robot Targeting System on Si Frame Tatsuya Ogiwara, Kazuto Okazaki, Shihou Takahama, Sinpei Yamasaki, Minami Takato, Ken Saito, Fumio Uchikoba, Nihon University / Japan</p>
Break				
10:50	<p>TA2: Taiwan Session-1 TA2-1 <Session Invited> TBD M J Kao, Industrial Technology Research Institute / Taiwan</p> <p>TA2-2 Low temperature bonding schemes for 3D chip stacking with fine pitch micro bump interconnections Chau-Jie Zhan, Industrial Technology Research Institute / Taiwan</p> <p>TA2-3 Thermal Performance of 3D IC Package with Embedded TSVs Ra-Min Tain, Industrial Technology Research Institute / Taiwan</p> <p>TA2-4 Cu/Ni/SnAg Microbump Bonding Processes for 30µm Pitch Thin-chip-on-chip Package Using a Wafer-level Underfill film Tsung-Fu Yang¹, Kuo-Shu Kao¹, Ren-Chin Cheng¹, Jing-Yao Chang¹, Chang-Chun Lee², Chau-Jie Zhan¹, Tai-Hong Chen¹, 1Industrial Technology Research Institute, 2Chung Yuan Christian University / Taiwan</p>	<p>TB2: Printed-2 TB2-1 <Session Invited> Fabrication of wire bonding pad by ink-jet printing using silver NanoPaste Satoshi Hisanaga, Harima Chemicals / Japan</p> <p>TB2-2 <Session Invited> Bondability of Copper Wires onto the Laser-Sintered Silver Pad Kazuhiko Yamasaki¹, Sumihiro Takahashi¹, Mamoru Mita², Katsuhiko Maekawa¹, Ibaraki University, 2M&M Research Laboratory / Japan</p> <p>TB2-3 <Session Invited> Silver nano paste as alternative to high temperature lead solder and example of die attachment using the paste Keiichi Endoh, DOWA Electronics Materials / Japan</p> <p>TB2-4 <Session Invited> Composition of the nanoparticle for Printed Electronics Hidekazu Hayama, KRI / Japan</p>	<p>TC2: Thermal-1 TC2-1 Energy Efficiency and Thermal Simulations of a Retrofit LED Light Bulb Mika Maaspuuro, University of Turku / Finland</p> <p>TC2-2 Thermal Characterization of a 60 GHz Frontend Phased Array System in Package on Board Wei-Ren Chiou, National Tsing Hua University / Taiwan</p> <p>TC2-3 Thermal Performance of Various Heat Sinks Lian-Tuu Yeh, Huawei Technologies / USA</p> <p>TC2-4 Sub-channel-inserted Porous Heat Sink for Cooling Future Power Devices Kazuhisa Yuki, Tokyo University of Science / Japan</p>	<p>TD2: MEMS-2 TD2-1 Mechanical and Electrical Characteristics of Direct Bonded Ge / Ge Interface Yuta Sasaki¹, Chenxi Wang¹, Eiji Higurashi¹, Tadamoto Suga¹, Yasuo Doi¹, Iwao Hosako², 1The University of Tokyo, 2National Institution of Information and Communication Technology / Japan</p> <p>TD2-2 Surface modification of polyethylene terephthalate (PET) by VUV and VUV/O₃ treatments for flexible capacitive tactile sensors Takashi Kasahara, Waseda University / Japan</p> <p>TD2-3 Residue-Free Plasma Etching of Polyimide Coatings Benjamin Mimoun¹, Hoa T. M. Pham², Vincent Henneken², Ronald Dekker^{1,2}, 1Delft University of Technology, 2Philips Research Eindhoven / The Netherlands</p> <p>TD2-4 New selective plasma treatment solution for streamlining MEMS manufacturing processes Ulrike Schoembs, SUSS MicroTec Lithography / Germany</p>
12:30				
Lunch				
13:30	<p>TA3: Taiwan Session-2 TA3-1 Thermal Management of a TSV Interposer with Moore's Law Chips on Both Sides for 3D IC Integration SiP Heng Chieh Chien, Industrial Technology Research Institute / Taiwan</p> <p>TA3-2 Active Layer of Organic Photovoltaic Devices Based on Conjugated Polymer Blending with PCBM Yi-Jiung Huang, Cho-Liang Chung, Jheng-Jih Pan, Sheng-Li-Fu, I-Shou University / Taiwan</p> <p>TA3-3 The study of photovoltaic devices using electrosput conjugated polymer fibers Sheng-Min Hung, Cho-Liang Chung, Yi-Shiang Chen, Sheng-Li-Fu, I-Shou University / Taiwan</p> <p>TA3-4 Electrical characteristics and reliability performance of a novel MOSFETs-embedded power module for mobile applications Yin-Po Hung, Sheng-Che Hung, Ren-Shin Cheng, Fang-Jun Leu, Jong-Shiou Peng, Chih-Ming Tzeng, Yu-Mei Cheng, Tao-Chih Chang, Tai-Hong Chen, Industrial Technology Research Institute / Taiwan</p>	<p>TB3: Printed-3 TB3-1 <Session Invited> Fine pitch copper wiring printed by Super inkjet Kazuhiro Murata^{1,2}, Naoki Shirakawa¹, Kazuyuki Masuda², 1Advanced Industrial Science and Technology, 2SIJTechnology / Japan</p> <p>TB3-2 <Session Invited> Compact gravure printing equipment Mini Lab Fine for new devices at Research and Development Yasuhisa Hashiguchi, Nihon Denshi Seiki / Japan</p> <p>TB3-3 <Session Invited> High density screen printing technology Hiroki Sato, Micro-tec / Japan</p> <p>TB3-4 Development of Copper Materials and Processing for Printed Electronics Kyoko Kuroda, Yasushi Kumashiro, Takaaki Noudou, Hitachi Chemical / Japan</p>	<p>TC3: MFG-1 TC3-1 Coating Quality Monitoring System Hiroshi Tsuruda, Koji Nishimura, Toray Engineering / Japan</p> <p>TC3-2 Effective Zeta Potential to Characterize Micromachined Glass Surface Yosuke Koga, Keio University / Japan</p> <p>TC3-3 Selective Formation of the Metal Film by Electroless Plating Process to ITO Daisuke Asakawa, Tadashi Kurashina, Yamato Denki Inc. / Japan</p> <p>TC3-4 Study on Palladium Removal in the Semi-Additive Process Kumiko Ishikawa, Hideomi Takahashi, Aya Goto, Juichi Tanimoto, Shozo Seino, Ebara-Udylite / Japan</p>	<p>TD3: DMR-1 TD3-1 Comparative Study of Dendrites Formation on ImAg and OSP Pad Finishes by Using Water Drop Test Kun Tang, Hong Kong University of Science and Technology / Hong Kong</p> <p>TD3-2 Simulation of Post-Mold Cure Process in IC Packaging Huy Tien Bui, National Cheng Kung University / Taiwan</p> <p>TD3-3 Simulation Assisted Physics of Failure based Reliability Assessment Mei-Ling Wu¹, Elvize George², and Michael Pecht^{2,3}, 1National Sun Yat-Sen University / Taiwan, 2University of Maryland / USA, 3City University of Hong Kong / Hong Kong</p> <p>TD3-4 Experimental Investigation of Creep Corrosion Masahiro Tsuruya, iNEMI / Japan</p>
15:10				
Poster Core Time				
15:40	<p>TA4: 3D-2 TA4-1 <Session Invited> Development of TSV/3D Memory+Logic SiP with 4k-I/O Interconnects Hiroaki Ikeda, Shiro Uchiyama, Atsushi Sakai, Harufumi Kobayashi, ASET / Japan</p> <p>TA4-2 Development of the high producing micro solder flip chip bonding process Daisuke Sakurai¹, Takatoshi Osumi¹, Kazuya Ushirokawa¹, Takashi Nakamura², Takatoshi Ishikawa², 1Panasonic, 2Panasonic Factory Solutions / Japan</p> <p>TA4-3 Modeling and Optimization on Signal and Power Integrity of Vertical Side-Chip Interconnection Jackson Kong¹, Bok Eng Cheah¹, Ai Heong Tan^{1,2}, 1Intel Microelectronics (M), 2Universiti Sains Malaysia / Malaysia</p> <p>TA4-4 A Built-in Electrical Test Circuit for Detecting Interconnect Open Defects in 3D ICs Tomoaki Konishi, The University of Tokushima / Japan</p>	<p>TB4: Printed-4 TB4-1 Preparation of Cu nano-particle in toluene used for conductive ink Song Li, Wuhan University of Technology / China</p> <p>TB4-2 Design and Packaging of a Flexible RFID Tag with Organic Photovoltaic and Nano Gas Sensors Jingyuan Huang, The Hong Kong University of Science and Technology / Hong Kong (16:30)</p>	<p>TC4: MFG-2 TC4-1 Homogenizing Piezoelectric Film and Application to Wafer Level Film Preparation Kazutaka Sueshige¹, Keita Iimura¹, Masaaki Ichiki^{1,3,4}, Tadamoto Suga¹, Toshihiro Itoh^{2,4}, 1The University of Tokyo, 2National Institute of Advanced Industrial Science and Technology, 3JST-PRESTO, 4JST-CREST / Japan</p> <p>TC4-2 Preparation and Characterization of PZT Thin Films on Releasable Substrate Erika Komine¹, Fumiaki Tomioka¹, Masaaki Ichiki^{1,3,4}, Tadamoto Suga¹, Toshihiro Itoh^{2,4}, 1The University of Tokyo, 2National Institute of Advanced Industrial Science and Technology, 3JST-PRESTO, 4JST-CREST / Japan</p> <p>TC4-3 Fabrication of Lead-free Dielectric Thin Film on Releasable Substrate Motoyuki Ozaki¹, Toshifumi Hosono¹, Masaaki Ichiki^{1,3,4}, Tadamoto Suga¹, Toshihiro Itoh^{2,4}, 1The University of Tokyo, 2National Institute of Advanced Industrial Science and Technology, 3JST-PRESTO, 4JST-CREST / Japan</p> <p>TC4-4 Structure and Process for Reducing Magnetic Minor Loop in Multilayer Ceramic Inductor Minami Takato, Aki Kenmochi, Toshiki Fujino, Ken Saito, Fumio Uchikoba, Nihon University / Japan</p>	<p>TD4: DMR-2 TD4-1 External Stress Effect to Electromigration on Thermal Annealed and Residue Stress Controlled Aluminum Strip Hsiang-Hung Chang, Kuo-Ning Chiang, National Tsing Hua University / Taiwan</p> <p>TD4-2 Reliability of Pb-free Solder Fatigue under Thermomechanical Conditions Yung-Wen Wang, National Sun Yat-Sen University / Taiwan</p> <p>TD4-3 Quick Assessment Approach of Lead-free Solder Joint Fatigue under Mechanical Bending Jia-Shen Lan, Mei-Ling Wu, National Sun Yat-Sen University / Taiwan (16:55)</p>
17:20				